

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hidekazu MIYAIRI et al.

Serial No. 10/663,671

Filed: September 17, 2003

For: LASER APPARATUS, LASER IRRADIATION
METHOD, AND MANUFACTURING METHOD
OF SEMICONDUCTOR DEVICE



) Group Art Unit: 1722
) Examiner: Hiteshew, Felisa Carla
)
Date: June 8, 2006

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed March 8, 2006, please consider the amendments and remarks in connection with the above-identified application as follows.